

**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (currently amended) In a MEMS device, the improvement comprising:  
a plurality of sensors electrically isolated from one another and positioned about an axis of symmetry to produce signals of substantially identical characteristics; and  
circuitry responsive to said plurality of sensors for comparing said signals produced by said plurality of sensors to identify asymmetries in said MEMS device.
2. (original ) The MEMS device of claim 1 additionally comprising circuitry for actuating the MEMS device.
3. (original ) The MEMS device of claim 1 wherein said MEMS device is implemented using batch-fabrication techniques, and wherein said circuitry and connections between said circuitry and said sensors are implemented using batch-fabrication techniques.
4. (original ) The MEMS device of claim 1 wherein said MEMS device is selected from the group consisting of resonators, accelerometers, gyroscopes, antennas, micromotors and ink jet print head microsystems.
5. (currently amended) A MEMS device, comprising:  
a plurality of fixed beams arranged symmetrically;  
a plurality of movable beams arranged symmetrically;  
a first sensor formed by certain of said fixed and movable beams;  
a second sensor, electrically isolated from said first sensor, and formed by at least certain other of said fixed and movable beams; and  
a circuit responsive to said first and second sensors for comparing signals produced by said first and second sensors to identify asymmetries in said MEMS device.
6. (original ) The device of claim 5 additionally comprising circuitry for actuating said plurality of movable beams.
7. (original ) The device of claim 5 wherein said MEMS device is implemented using batch-fabrication techniques, said circuit and connections between said circuit and said sensors are implemented using batch-fabrication techniques.

8. (currently amended) In a symmetric MEMS device, the improvement comprising:

a plurality of sensors positioned about an axis of symmetry to produce signals of substantially identical characteristics; and

circuitry responsive to said plurality of sensors for real time comparison of said signals produced by said plurality of sensors.

9. (original ) The MEMS device of claim 8 additionally comprising circuitry for actuating the MEMS device.

10. (original ) The MEMS device of claim 8 wherein said MEMS device is implemented using batch-fabrication techniques, said circuitry and connections between said circuitry and said sensors are implemented using batch-fabrication techniques.

11. (original ) The MEMS device of claim 8 wherein said MEMS device is selected from the group consisting of resonators, accelerometers, gyroscopes, antennas, micromotors and ink jet print head microsystems.

12. (original ) A MEMS device, comprising:

a plurality of fixed beams arranged symmetrically;

a plurality of movable beams arranged symmetrically;

a first sensor formed by certain of said fixed and movable beams;

a second sensor formed by at least certain other of said fixed and movable beams; and

a circuit responsive to said first and second sensors for real time comparison of said signals produced by said sensors.

13. (original ) The MEMS device of claim 12 additionally comprising circuitry for actuating said plurality of movable beams.

14. (original ) The MEMS device of claim 12 wherein said MEMS device is implemented using batch-fabrication techniques, said circuit and connections between said circuit and said sensors are implemented using batch-fabrication techniques.

15 – 27. Canceled.